

Claims:

1       1. A device for in-situ measurement and recording of at least one parameter in a  
2 process, said device comprising:

3           a sensor for detecting said parameter and converting to a sensor output; and  
4           a data logger coupled to said sensor for receiving and logging said sensor output.

1       2. The device of claim 1 wherein said data logger comprises a timestamping module  
2 for recording a timestamp with said sensor output.

1       3. The device of claim 2 further comprising a communication module for  
2 communicating said sensor output.

1       4. The device of claim 3 wherein said communication module comprises a  
2 transmitter and a receiver.

1       5. The device of claim 3 wherein said communication module comprises an RF  
2 (radio frequency) communication module.

1       6. The device of claim 1 further comprising a display device.

1       7. The device of claim 1 wherein said sensor is configured to detect a presence of  
2 electrostatic field.

1       8. The device of claim 7 wherein said sensor is configured to measure a magnitude  
2 of said electrostatic field.

1       9. The device of claim 8 wherein said sensor is configured to detect a change in said  
2 electrostatic field.

1       10. The device of claim 1 wherein said sensor is configured to detect an electrostatic  
2 discharge.

1           11.    The device of claim 10 wherein said sensor is configured to measure a magnitude  
2    of said electrostatic discharge.

1           12.    The device of claim 1 wherein said data logger comprises an analog to digital  
2    converter (ADC) to convert said sensor output into digital data.

1           13.    The device of claim 12 further comprising signal processing circuitry coupled to  
2    said sensor for processing said sensor output.

1           14.    A device for in-situ measurement and recording of at least one parameter in a  
2    process, said device comprising:

3           means for detecting said parameter and converting to a sensor output; and  
4           means for receiving and logging said sensor output.

1           15.    The device of claim 14 wherein said means for receiving and logging comprises a  
2    timestamping module for recording a timestamp with said sensor output.

1           16.    The device of claim 13 further comprising means for communicating said sensor  
2    output.

1           17.    The device of claim 16 wherein said means for communicating comprises a  
2    transmitter and a receiver.

1           18.    The device of claim 16 wherein said means for communicating comprises an RF  
2    (radio frequency) communication module.

1           19.    A method for in-situ measurement and recording of at least one parameter in a  
2    semiconductor fabrication process comprising a plurality of stages, said method comprising:

3           (a)    monitoring said parameter in a stage of said plurality of stages;  
4           (b)    converting said parameter into data;  
5           (c)    logging said data and an identification of said stage; and  
6           (d)    repeating (a) – (d) for said plurality of stages.

1           20.    The method of claim 19 further comprising timestamping said data.

1           21.    The method of claim 20 further comprising signal processing said data.

1           22.    The method of claim 21 further comprising converting said data into digital data.

1           23.    The method of claim 22 further comprising communicating said digital data and

2    said identification of said stage to a base equipment.

1           24.    The method of claim 23 wherein said parameter comprises electrostatic field.

1           25.    The method of claim 24 wherein said parameter comprises a change in said

2    electrostatic field.

1           26.    The method of claim 25 wherein said parameter comprises an electrostatic

2    discharge.

1           27.    The method of claim 26 further comprising eliminating extraneous electrostatic

2    discharges based on said electrostatic discharge and said electrostatic field.

1           28.    A device for in-situ monitoring of at least one environmental parameter in a

2    photolithographic process comprising a plurality of stages, said device comprising:

3           at least one sensor for converting said environmental parameter of an associated stage

4    into a sensor output;

5           an analog to digital converter for converting said sensor output to digital data; and

6           a communication module to communicate said digital data and an identification of said

7    associated stage of said plurality of stages.

1           29.    The device of claim 28 further comprising a data logger for logging said digital

2    data and said identification of said associated stage.

1           30.    The device of claim 29 wherein said communication module comprises a

2    transmitter and a receiver.

1           31.    The device of claim 29 wherein said communication module comprises an RF  
2 (radio frequency) communication module.

1           32.    The device of claim 28 further comprising a display device.

1           33.    The device of claim 28 further comprising a sensor for detecting a presence of  
2 electrostatic field.

1           34.    The device of claim 33 wherein said sensor is configured to measure a magnitude  
2 of said electrostatic field.

1           35.    The device of claim 34 wherein said sensor is configured to detect a change in  
2 said electrostatic field.

1           36.    The device of claim 28 further comprising a sensor for detecting an electrostatic  
2 discharge.

1           37.    The device of claim 36 wherein said sensor is configured to measure a magnitude  
2 of said electrostatic discharge.

1           38.    The device of claim 28 further comprising signal processing circuitry coupled to  
2 said plurality of sensors for processing said sensor output.

1           39.    A device for use in conjunction with a reticle for in-situ monitoring of at least one  
2 electrical parameter in a semiconductor fabrication process comprising a plurality of stages, said  
3 device comprising:

4           a sensor for converting said electrical parameter of a stage into a sensor output;

5           an analog to digital converter for converting said sensor output to digital data;

6           a data logger comprising a timestamping module for logging said digital data and an  
7 identification of said stage; and

8           an RF (radio frequency) communication module coupled to said data logger.

1           40.    The device of claim 39 wherein said electrical parameter comprises electrostatic  
2    field.

1           41.    The device of claim 39 wherein electrical parameter comprises an electrostatic  
2    discharge.

1           42.    A method for in-situ measurement and recording of at least one parameter in a  
2    semiconductor fabrication process comprising at least one stage, said method comprising:

- 3           (a)    monitoring said parameter in said stage;
- 4           (b)    converting said parameter into data; and
- 5           (c)    logging said data and an identification of said stage.

1           43.    The method of claim 42 further comprising  
2    timestamping said data.

1           44.    The method of claim 43 further comprising:  
2    signal processing said data.

1           45.    The method of claim 44 further comprising:  
2    converting said data into digital data.

1           46.    The method of claim 44 further comprising:  
2    communicating said digital data and said identification of said stage to a base equipment.

1           47.    The method of claim 46 wherein said parameter comprises electrostatic field.

1           48.    The method of claim 46 wherein said parameter comprises an electrostatic  
2    discharge.

1           49.    A device for monitoring environmental parameters comprising:  
2           an electrostatic sensor for detecting electrostatic field and converting said electrostatic  
3    field into a first output;

4           an electrostatic discharge (ESD) sensor for detecting an electrostatic discharge and  
5   converting said electrostatic discharge into a second sensor output;

6           an analog to digital converter coupled to said electrostatic sensor and said ESD sensor for  
7   converting said first and second sensor outputs to first and second digital data, respectively; and

8           a data logger comprising a timestamping module for logging said first and second digital  
9   data.

1           50.    The device of claim 49 further comprising an RF (radio frequency)  
2   communication module coupled to said data logger.

1           51     A method for localizing electrostatic discharges (ESD) by detecting electrostatic  
2   discharges and electrostatic field, the method comprising:

3           detecting an electrostatic discharge and converting it into a first output;

4           detecting said electrostatic field and converting it into a second output; and

5           determining a valid local electrostatic discharge based on said first and second outputs.

1           52.    The method of claim 51 wherein said determining comprises determining said  
2   valid local electrostatic discharge when said electrostatic discharge is combined with said  
3   electrostatic field having a magnitude that exceeds a predetermined value.

1           53.    The method of claim 52 further comprising converting said first and second  
2   outputs to first and second digital data, respectively.

1           54.    A device for localizing electrostatic discharges affecting a unit by detecting an  
2   electrostatic discharge and electrostatic field, the device comprising:

3           an electrostatic sensor for detecting said electrostatic field affecting said unit and  
4   generating a first output; and

5           an ESD sensor for detecting said electrostatic discharge affecting said unit and generating  
6   a second output.

1           55.    The device of claim 54 further comprising:

2           an analog comparator coupled to said first output for generating a comparator output  
3 when said electrostatic field has a magnitude exceeding a predetermined value.

1           56.    The device of claim 55 further comprising:  
2            a circuit coupled to said analog comparator and to said ESD sensor for receiving said  
3            comparator output and said second output, said circuit configured to generate a valid ESD signal  
4 when said comparator output and said second output are detected.

1           57.    The device of claim 54 further comprising:  
2            an analog to digital converter (ADC) coupled to said electrostatic sensor and said ESD  
3            sensor for converting said first and second outputs to first and second digital data, respectively.

1           58.    The device of claim 57 further comprising:  
2            a digital comparator coupled to said first data and generating a comparator output when  
3 said electrostatic field has a magnitude exceeding a predetermined value.

1           59.    The device of claim 58 further comprising:  
2            a circuit coupled to said digital comparator and to said ADC for receiving said  
3            comparator output and said second data, said circuit configured to generate a valid ESD signal  
4 when said comparator output and said second data are detected.

1           60.    The device of claim 59 wherein said circuit is an AND gate.

1           61.    The device of claim 60 further comprising:  
2            a data logger comprising a timestamping module for logging said first and second digital  
3 data.

1           62.    The device of claim 61 further comprising an RF (radio frequency)  
2 communication module coupled to said data logger.

1           63.    A method for localizing electrostatic discharges (ESD) by detecting electrostatic  
2 discharges and electrostatic field, the method comprising:  
3            detecting an electrostatic discharge and converting it into a first output;

4           detecting a change in said electrostatic field and converting it into a second output; and  
5           determining a valid local electrostatic discharge based on said first and second outputs.

1           64.       The method of claim 63 wherein said determining comprises determining said  
2        valid local electrostatic discharge when said electrostatic discharge is combined with said  
3        electrostatic field changing at a rate that exceeds a predetermined value.

1           65.       The method of claim 64 further comprising converting said first and second  
2        outputs to first and second digital data, respectively.

1           66.       A device for localizing electrostatic discharges affecting a unit by detecting an  
2        electrostatic discharge and electrostatic field;  
3        an electrostatic sensor for detecting a change in said electrostatic field and generating a  
4        first output; and  
5        an ESD sensor for detecting said electrostatic discharge and generating a second output.

1           67.       The device of claim 66 further comprising:  
2        a high pass filter coupled to said first output for generating a high pass filter output when  
3        said electrostatic field changes at a rate exceeding a predetermined value.

1           68.       The device of claim 67 further comprising:  
2        a circuit coupled to said high pass filter and to said ESD sensor for receiving said high  
3        pass filter output and said second output, said circuit configured to generate a valid ESD signal  
4        when said high pass filter output and said second output are detected.

1           69.       The device of claim 68 further comprising:  
2        an analog to digital converter (ADC) coupled to said electrostatic sensor and said ESD  
3        sensor for converting said first and second outputs to first and second digital data, respectively.

1           70.       The device of claim 69 further comprising:  
2        a high pass filter coupled to said first data for generating a high pass filter output when  
3        said electrostatic field changes at a rate exceeding a predetermined value.

1           71.    The device of claim 70 wherein said high pass filter comprises software codes  
2 executable by a microprocessor.

1           72.    The device of claim 70 further comprising:  
2            a circuit coupled to said high pass filter and to said ADC for receiving said high pass  
3 filter output and said second data, said circuit configured to generate a valid ESD signal when  
4 said high pass filter output and said second data are detected.

1           73.    The device of claim 72 wherein said circuit is an AND gate.

1           74.    The device of claim 73 further comprising:  
2            a data logger comprising a timestamping module for logging said first and second digital  
3 data.

1           75.    The device of claim 74 further comprising an RF (radio frequency)  
2 communication module coupled to said data logger.